

Analysis of the Photodegradation at 157 nm of Photolithographic-Grade Teflon® AF Pellicles

*Idriss Blakey†, Graeme A. George‡, David J. T. Hill§, Heping Liu†, Firas
Rasouf†, Llew Rintoul ‡, Andrew K. Whittaker†, Paul Zimmerman¥*

† Centre for Magnetic Resonance, University of Queensland, Australia

‡ School of Physical Sciences, Queensland University of Technology,
Australia

§ School of Microbial and Molecular Science, University of Queensland,
Australia.

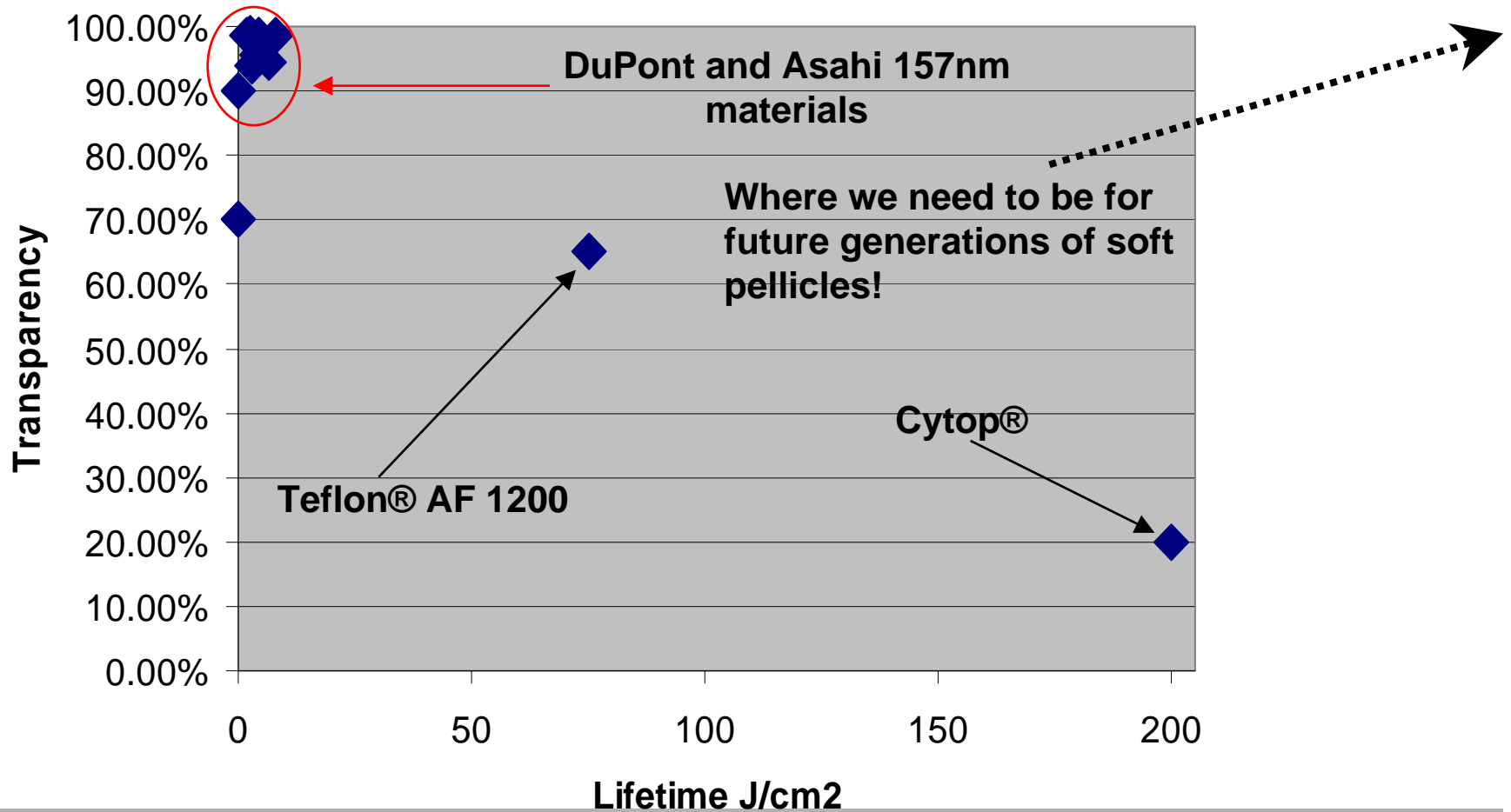
¥ International SEMATECH, USA

Pellicle Requirements for 157 nm

- The requirements for 157 nm soft pellicles were
 - materials with >95% transparency at 157nm
 - exposure lifetimes of 3 kJ/cm²
 - <1% deviation in transparency during this period

Current Materials for Soft Pellicles

Material Transparency vs. Lifetime

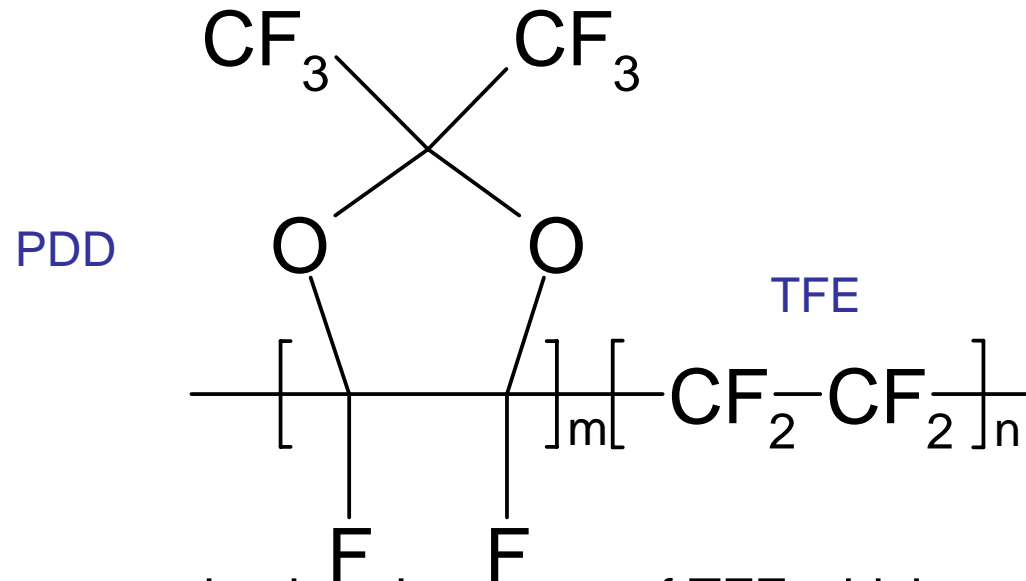


Aims of this Study

- To understand photodegradation mechanisms of Teflon® AF type copolymers so that polymers with improved lifetimes and transparency could be designed

Polymers Studied

- Teflon® AF 1200 (PDD:TFE, 48:52)
- Teflon® AF 1600 (PDD:TFE, 65:35)
- Teflon® AF 2400 (PDD:TFE, 89:11)

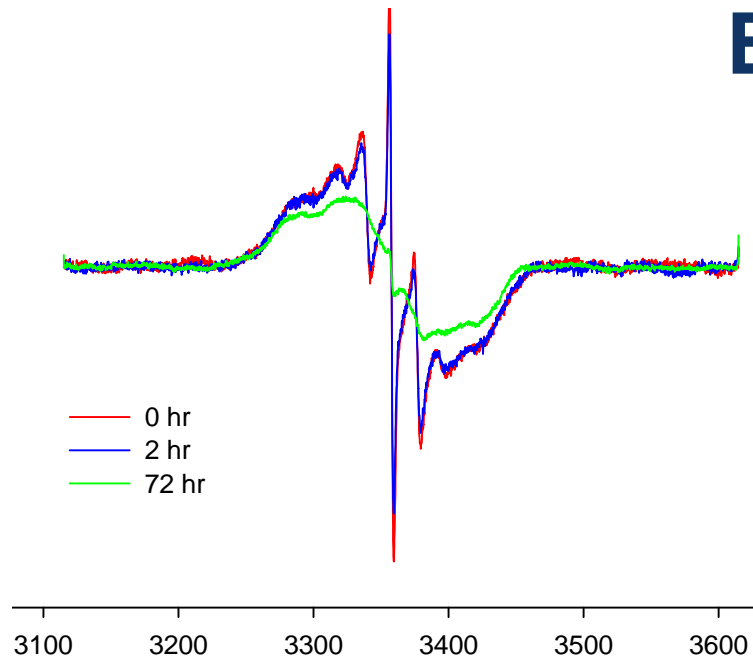


- PDD units incorporated to break up runs of TFE which results in increased transparency
- Generally polymers studied as thin films
 - Spin coated from Fluorinert solutions onto CaF₂

Instrumentation Used

- Electron Spin Resonance (ESR)
 - Presence of radicals
- X-ray Photoelectron Spectroscopy (XPS)
 - Atomic ratio changes and changes in functionality
- Raman Microscopy
 - Effect of polymer sequence
- ^{19}F Nuclear Magnetic Resonance (NMR)
 - Changes in functionality
- FT-Infrared (FTIR)
 - Changes in functionality
- Mass Spectrometry (MS)
 - Low molecular weight fragments

ESR

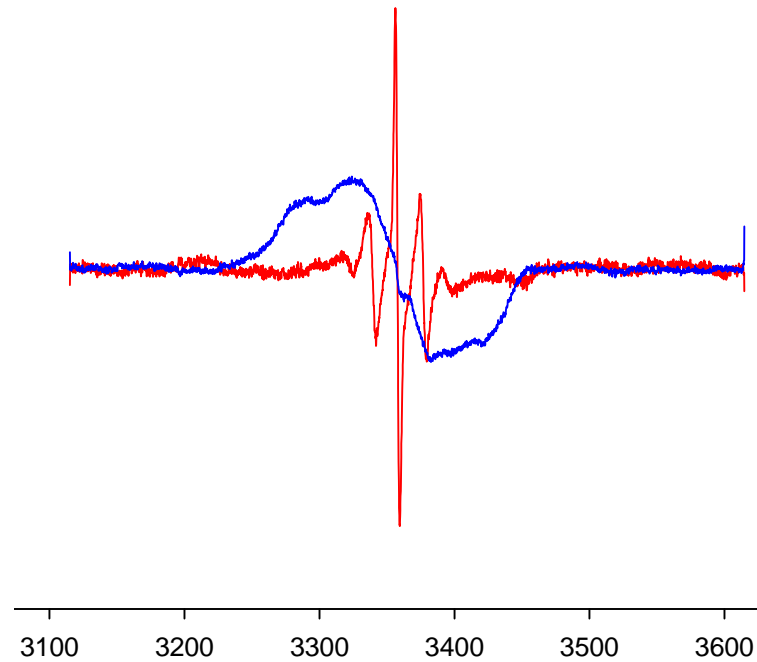


TAF1600

Field (G)

immediately after 20 J irradiation (red),
2 hours after irradiation (blue)
72 hours after irradiation (green).

- radicals are involved in process
- More than one species present
 - Short lived mobile (chain end?) radicals
 - Long lived radicals on the backbone (from loss of F^{\bullet} ?)

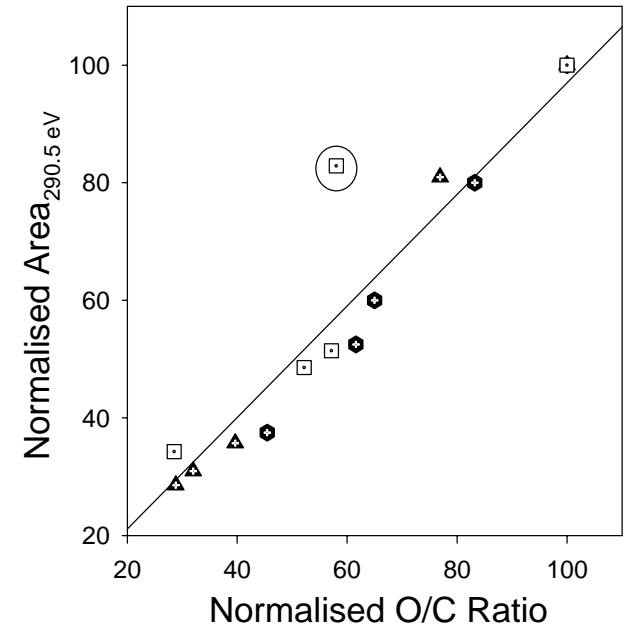
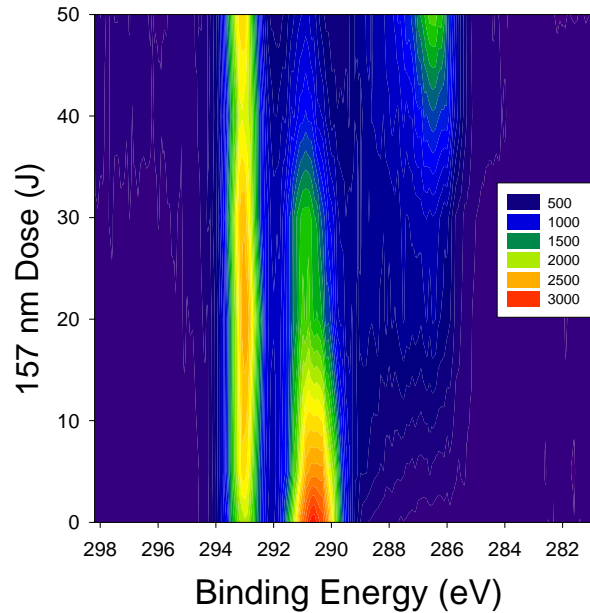
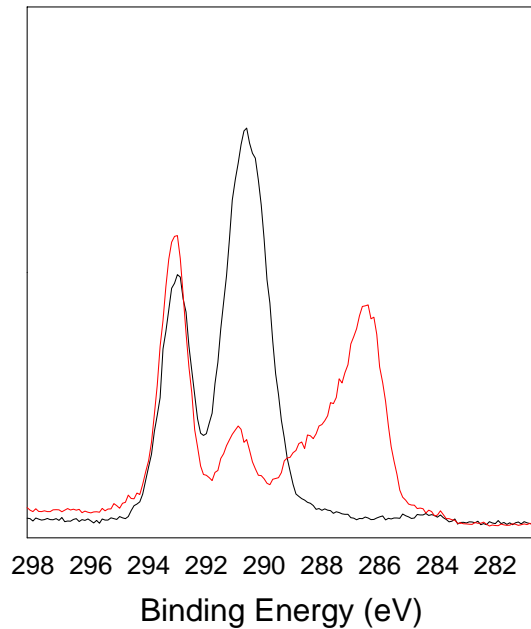


TAF1600

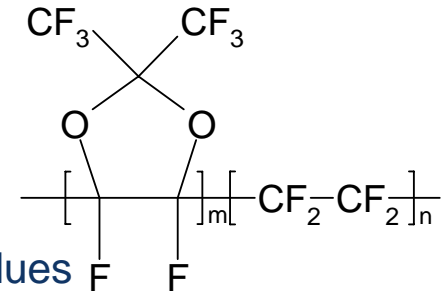
Field (G)

Long lived species (blue),
Short lived species (red)

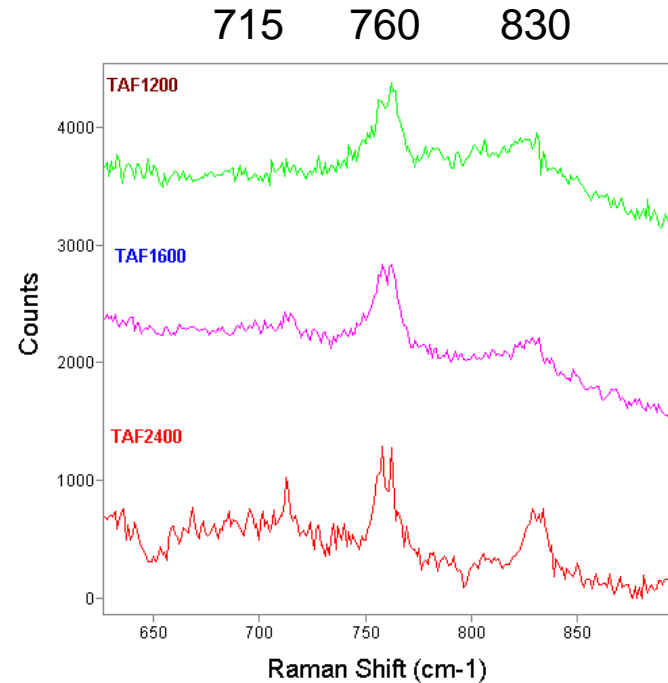
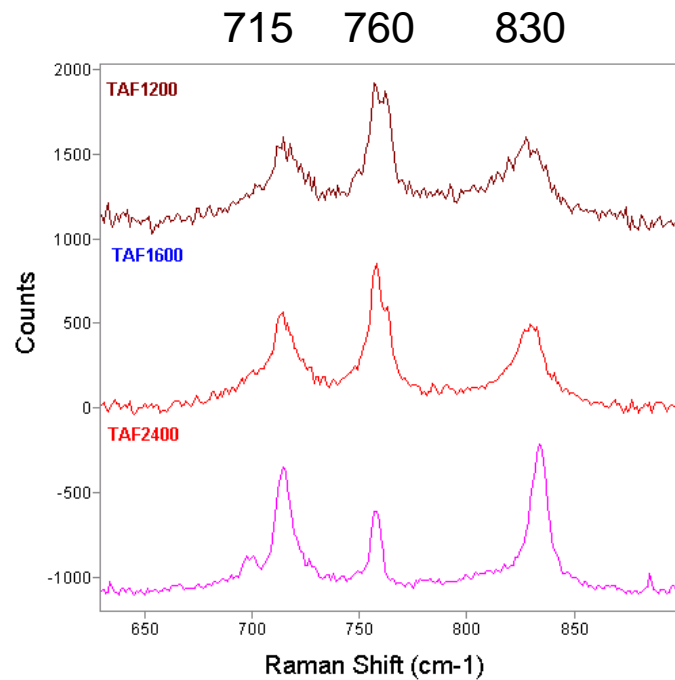
XPS Results



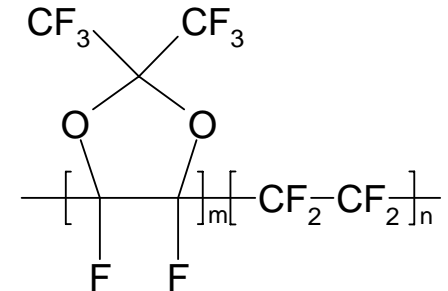
- **Dramatic decrease in O\C**
 - Infers formation of oxygen containing small molecules
 - Degradation predominantly occurs in dioxole ring
- **Decrease in F\C**
 - Extensive defluorination and formation of carbonized residues
- **-CF₃ degradation products dominate**
- **Rate of degradation of TAF2400 much faster than for other copolymers**



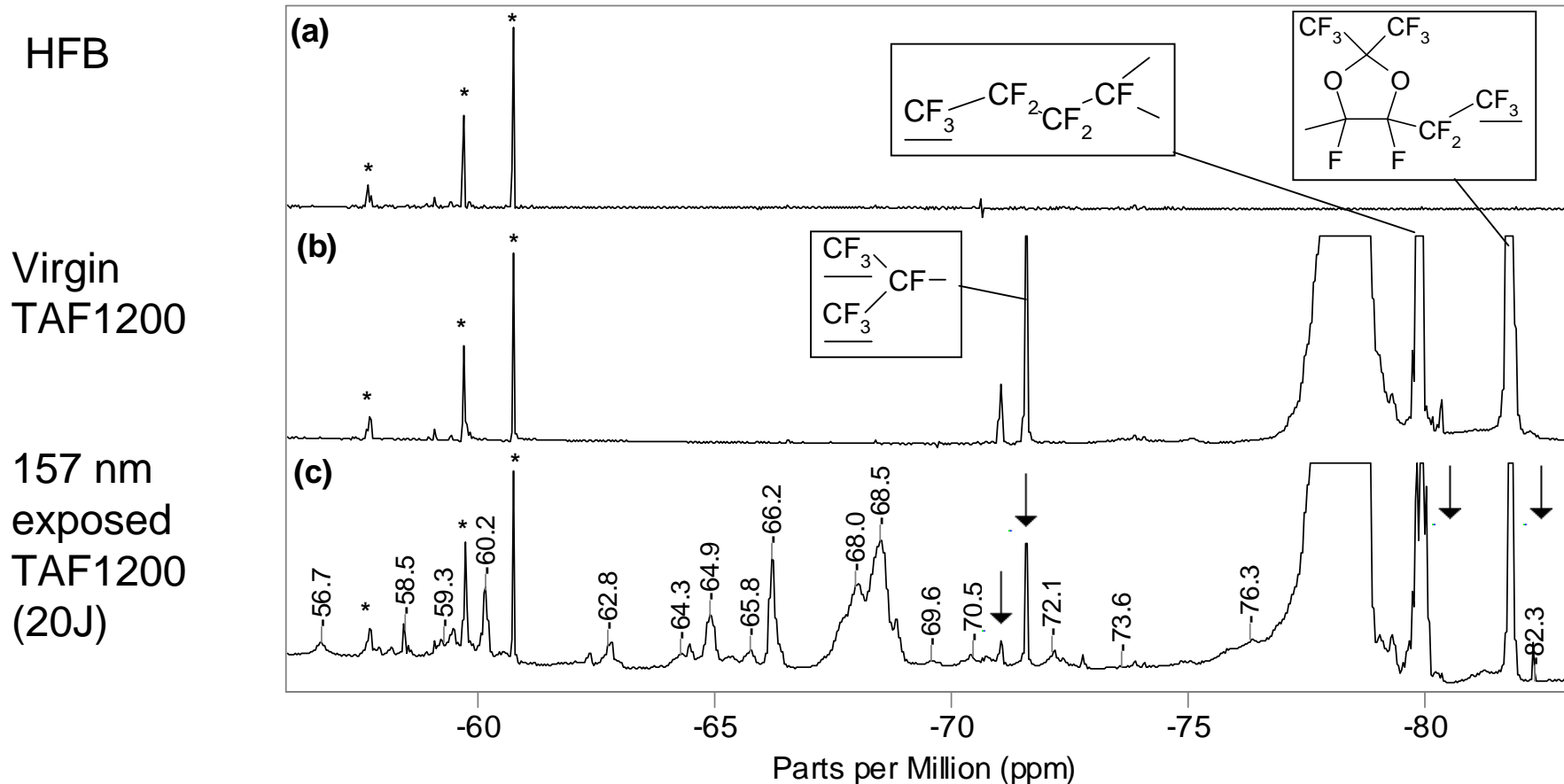
Raman Results



- 715 cm⁻¹ peak due to vibration involving (CF₃)₂-C-O₂
- 760 cm⁻¹ peak due to vibration involving CF₂
- 830 cm⁻¹ peak due to vibration involving CF-CF
- Degradation occurs predominately in the dioxole ring
 - (CF₃)₂-C-O₂ portion in particular, probably via C-O scission
 - Series of dioxole rings are more susceptible to degradation



Solution ^{19}F NMR Results

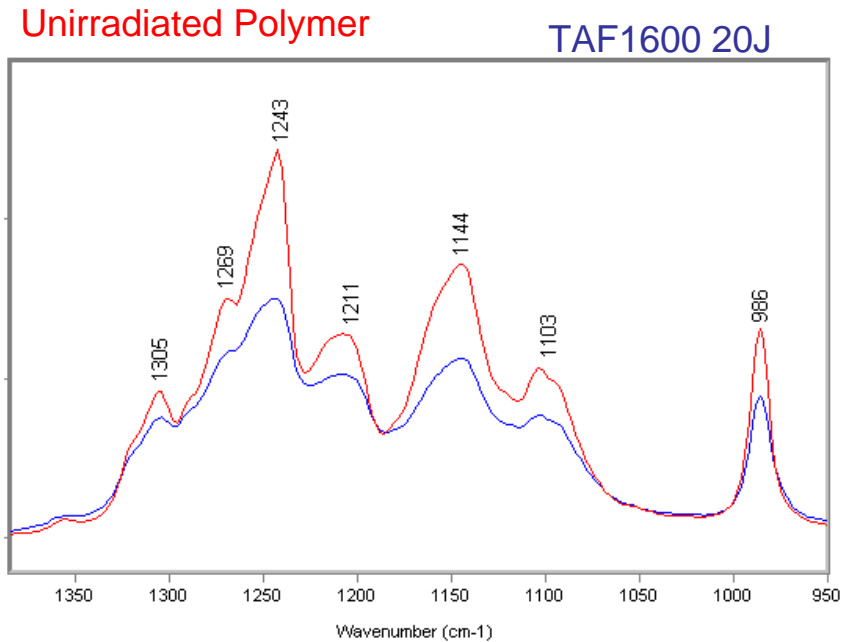
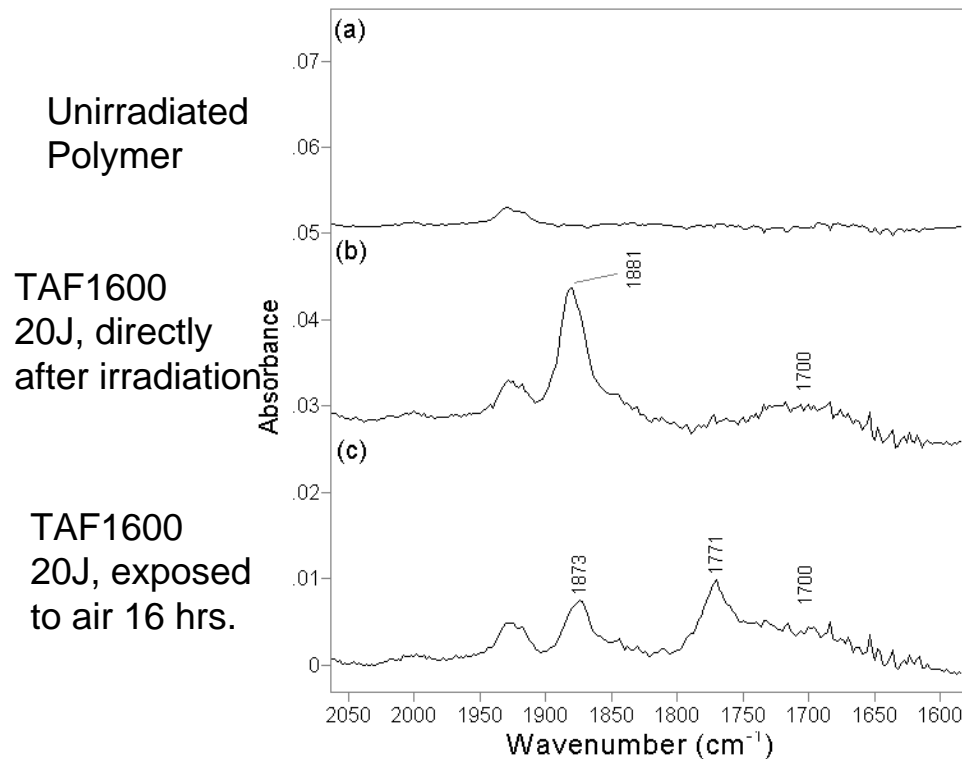


- After 157 nm irradiation polymer residues contain a large number of $-\text{CF}_3$ type structures
- Similar scenario for TAF1600 and TAF 2400

^{19}F NMR Peak Assignments

- Peaks were compared to ^{19}F NMR spectral database
 - Peaks present were consistent with $-\text{CF}_3$ containing groups
 - Some peaks were consistent with unsaturated groups
 - Presence of $-\text{CF}_3$ groups is consistent with XPS data
- Unsaturated products consistent with defluorination that was observed with XPS
- Degradation products are predominately derived from dioxole groups, which is consistent with XPS and Raman data

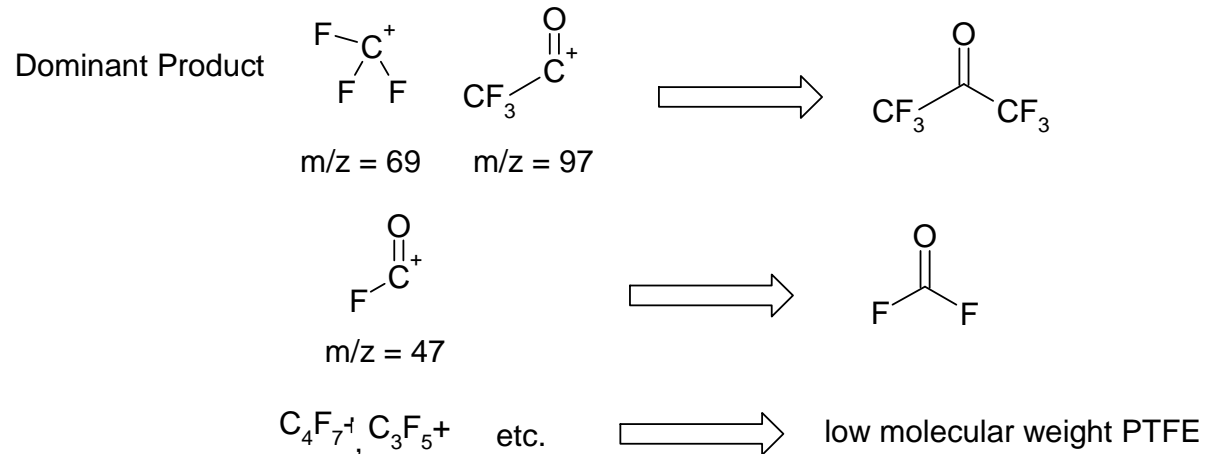
FTIR Results



- Observe Acid Fluoride and possibly vinyl group formation
- Acid fluoride at 1873 cm⁻¹ confirmed by observing conversion to acid at 1771 cm⁻¹
- Observe dramatic film thinning upon exposure to 157 nm light
- Similar scenario occurs for TAF1200 and 2400
- Acid Fluoride reaches a steady state concentration
 - Indicates that it undergoes secondary reactions

MS Results

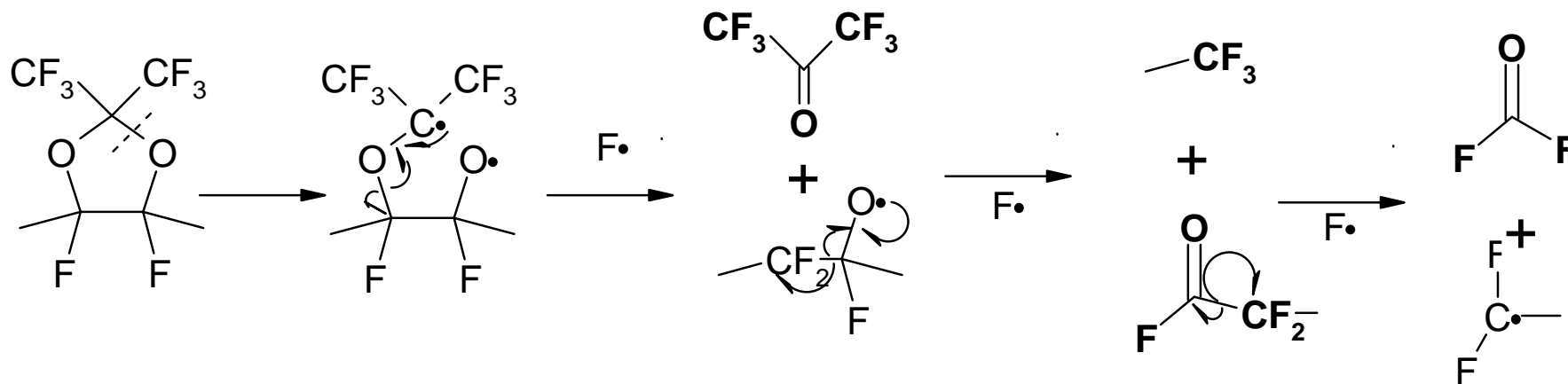
- Nitrogen purge gas from degradation cell was passed through liquid nitrogen cold finger.
- Gas collected was analysed by MS
- Large number of low molecular weight fragments observed ($m/z < 200$).
 - Eg



Recap of Results

- Mechanism involves
 - Free radicals (ESR)
 - Mobile $-\text{CF}_2\bullet$ radicals
 - Degradation predominantly at the dioxole ring (Raman, XPS)
 - Formation of $-\text{CF}_3$ end groups (XPS, NMR)
 - Formation of Acid Chlorides (FTIR)
 - Extensive loss of small molecules (FTIR, MS)
 - Formation of unsaturated and graphitic structures (XPS, NMR, FTIR)

Proposed Dominant Mechanism



- Hexafluoroacetone formation consistent with :
 - Forsythe, J. S.; Hill, D. J. T.; Logothetis, A. L.; Whittaker, A. K. *Polym. Deg. Stab.* **1999**, 63, 95-101.
- Carbonyl difluoride consistent with
 - Tonelli, C.; Tortelli, V. *J. Fluor. Chem.* **2000**, 101, 117-123

Recap of Results

- Mechanism involves
 - Free radicals (ESR) ✓
 - Mobile $-\text{CF}_2\cdot$ radicals ✓
 - Degradation predominantly at the dioxole ring (Raman, XPS) ✓
 - Formation of $-\text{CF}_3$ end groups (XPS, NMR) ✓
 - Formation of Acid Chlorides (FTIR) ✓
 - Extensive loss of small molecules (FTIR, MS) ✓
 - Formation of unsaturated and graphitic structures (XPS, NMR)
Occurs via secondary reactions of primary degradation products

Conclusions

Photodegradation of TAF polymers at 157 nm occurs primarily at the dioxole ring.

- Particularly runs of dioxole units
- Degradation occurs at a much faster rate for TAF2400
- Dioxole ring structure can not be incorporated into future pellicle designs for 157 nm lithography
- Other strategies to break up runs of TFE units need to be used

Other Materials

- Cross-linked PTFE or polyperfluoroethers?
 - Discussed in next talk

Acknowledgements

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